

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Shunpei YAMAZAKI et al.

Serial No. 10/072,931

Filed: February 12, 2002

For: METHOD OF MANUFACTURING
A SEMICONDUCTOR DEVICE

-) Art Unit: Unknown
Examiner: Unknown
(
)(
) (S)

2812

INFORMATION DISCLOSURE STATEMENTCommissioner for Patents and Trademarks
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application. Copies of the references are submitted herewith in accordance with 37 C.F.R. 1.98(a).

The Examiner's attention is particularly directed to JP 05-109737, which discloses a gettering by using argon gas.

The documents are being submitted within 3 months of the filing, or entry into the national phase, of this application or before the first Office Action on the merits, whichever is later, therefore no fee or certification is required under 37 C.F.R. § 1.97(b).

The Commissioner is hereby authorized to charge fees under 37 C.F.R. §§1.16, 1.17, 1.20(a), 1.20(b), 1.20(c), and 1.20(d) (except the Issue Fee) which may be required now or hereafter, or credit any overpayment to Deposit Account No. 19-2380 (740756-2433).

Respectfully submitted,


 Eric J. Robinson
 Registration No. 38,285

 Nixon Peabody LLP
 8180 Greensboro Drive, Suite 800
 McLean, Virginia 22102
 (703) 790-9110

RECEIVED
APR 23 2002
TECHNOLOGY CENTER 2800